

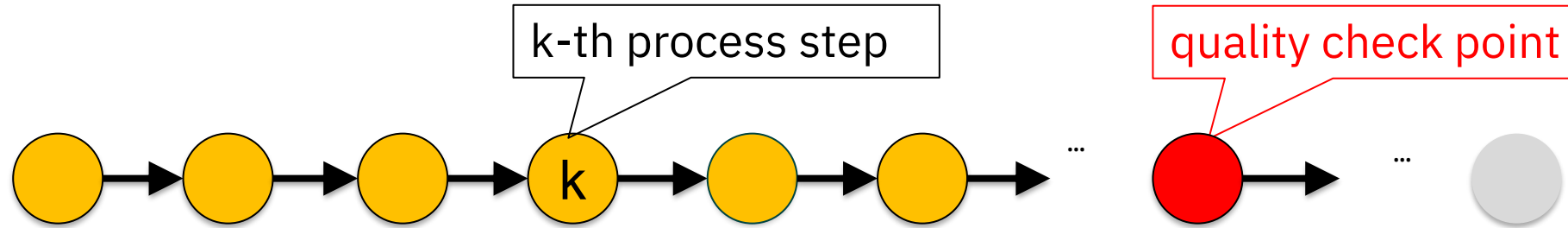


Tsuyoshi (Ide-san) Ide

Partial Trajectory Analysis for Diagnosing Sequential Manufacturing Processes

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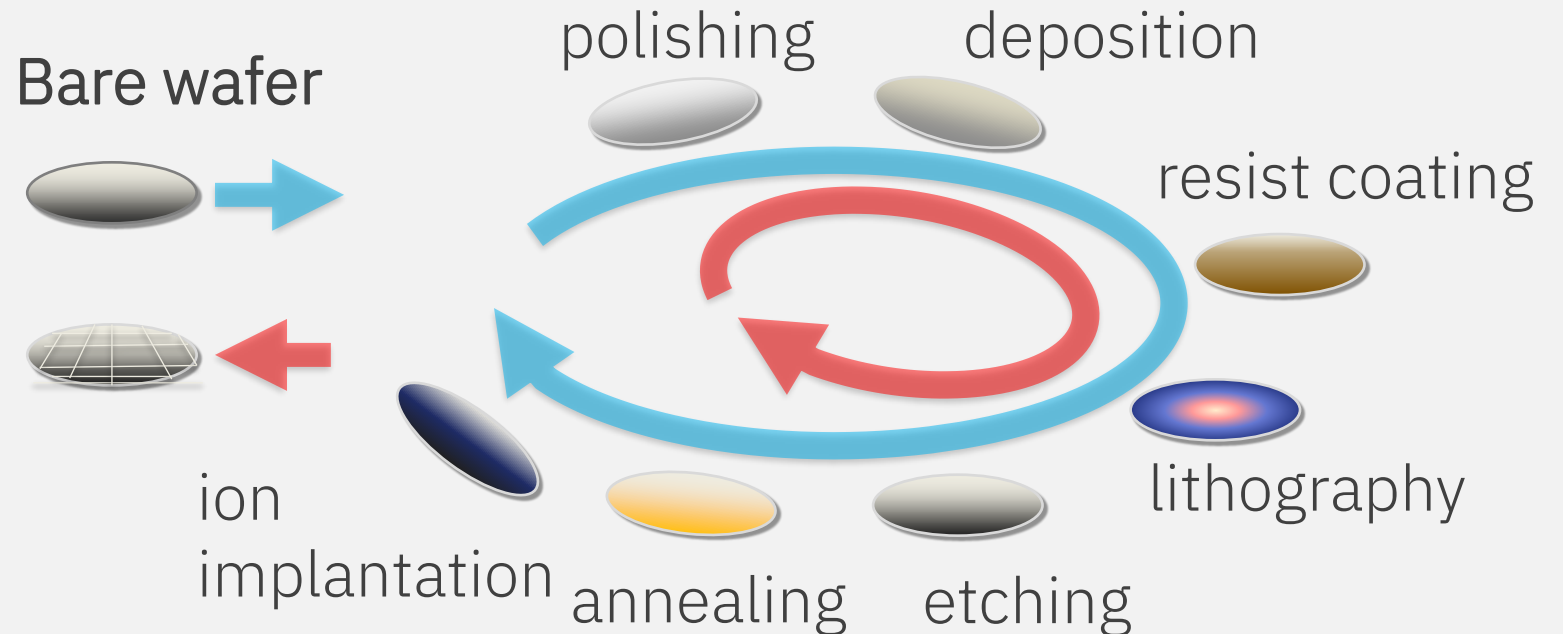
Target task: cross-process defect attribution



Example: Semiconductor Manufacturing

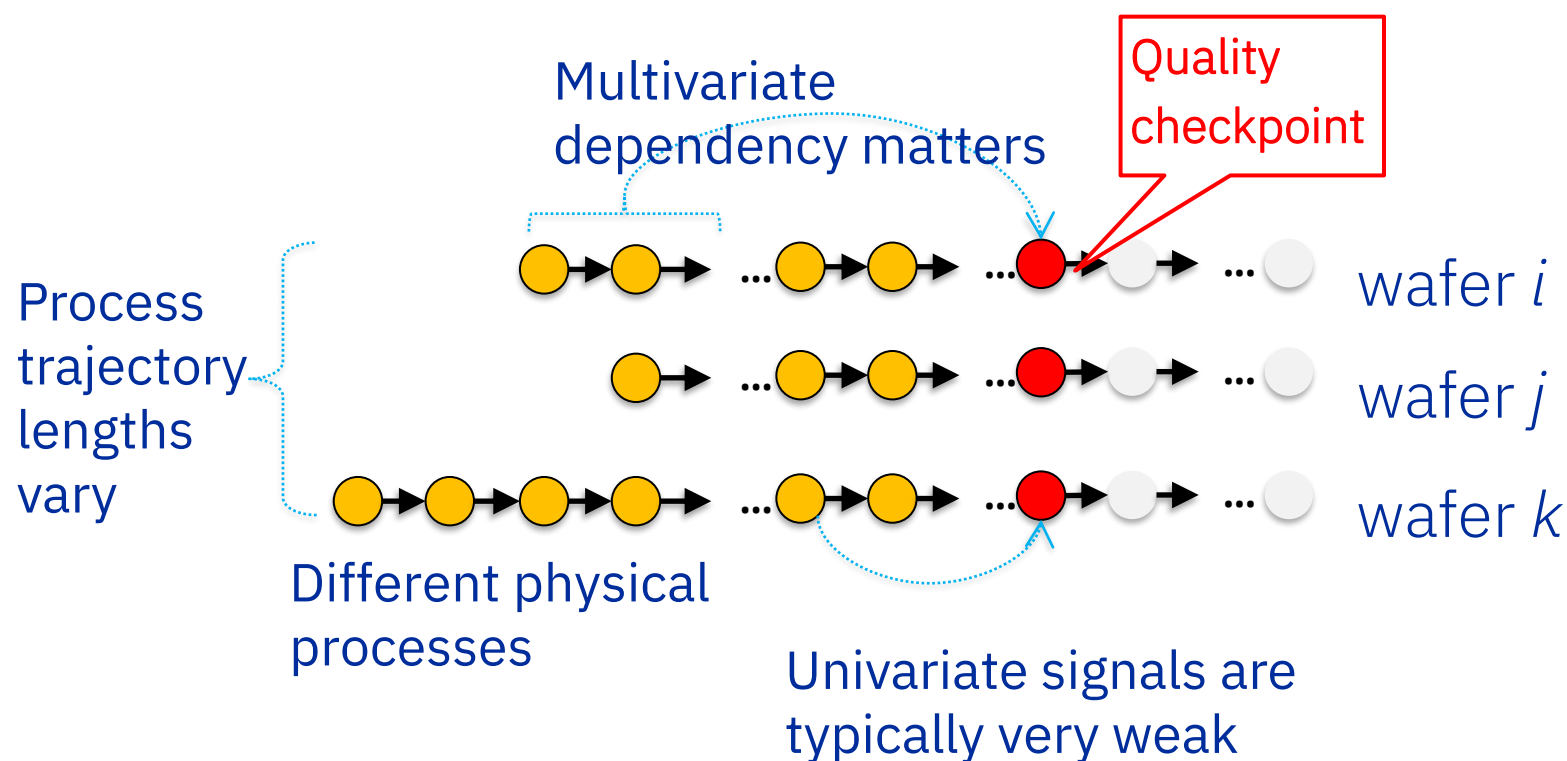
FEOL: device
fabrication

BEOL: wiring
formation



Target task: cross-process defect attribution

Problem: Given a wafer quality metric value, compute the **attribution score** for each of the upstream process steps.

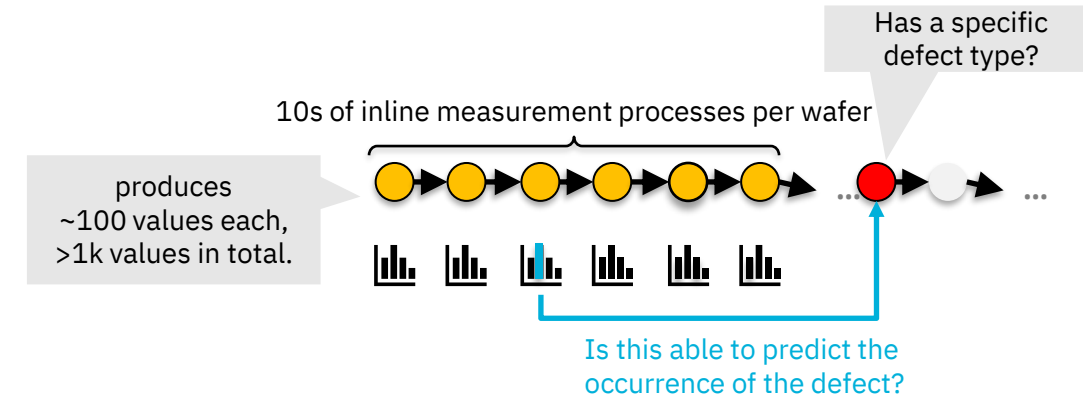


■ In current practice...

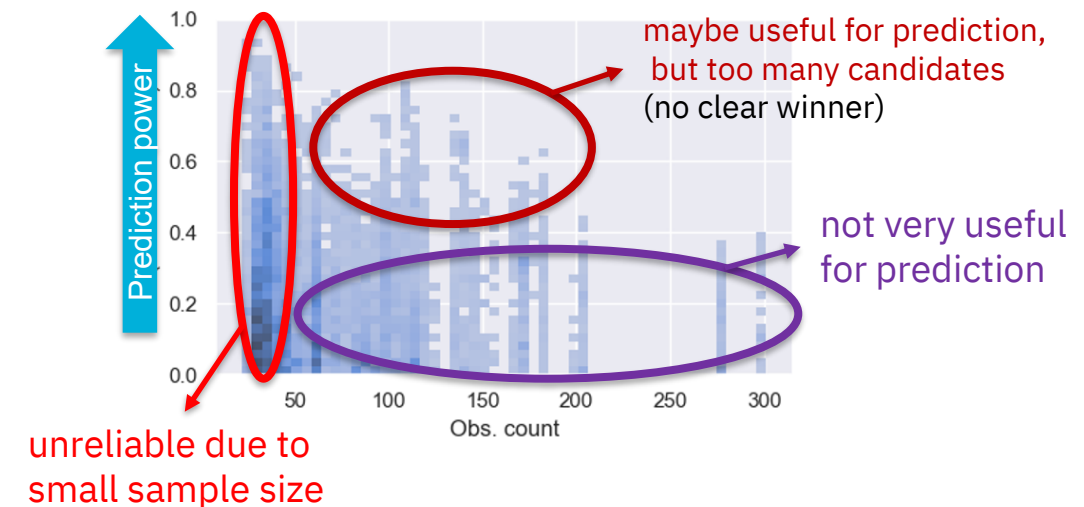
- The only viable approach is to run as many wafers as possible under varying conditions.
- Then, relatively simple statistical analysis is applied.
- This approach requires significant domain expertise to decide on parameter choices.
- This semi-manual approach is reaching its limits as technology nodes advance.

Univariate correlation is often not informative

- In test production, 10s of inline measurements produces 1K+ measurement numbers for each wafer.
- Univariate analysis typically does not give strong signal.
 - Trained a univariate binary classifier to distinguish between good and bad wafers.
 - Accuracy tends to decrease as the observation count increases.
- Process engineers usually focus on a limited number of measurement items based on prior knowledge.



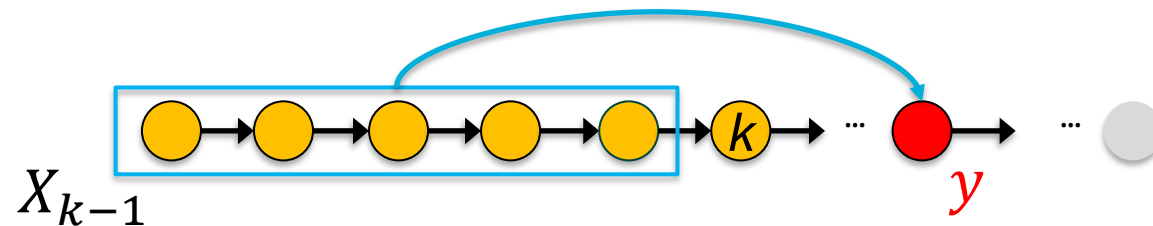
Defect occurrence prediction with single measurement values



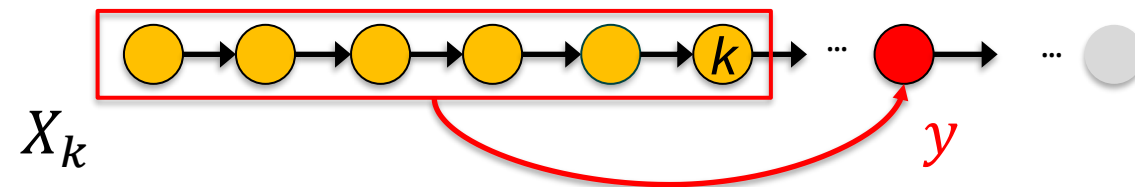
Partial trajectory analysis (PTA) approach: Key idea

- PTA computes the attribution score of the k -th process by evaluating the impact of k 's "participation" in the process trajectory.

A: Prediction using a partial trajectory **not** including k



B: Prediction using a partial trajectory including k



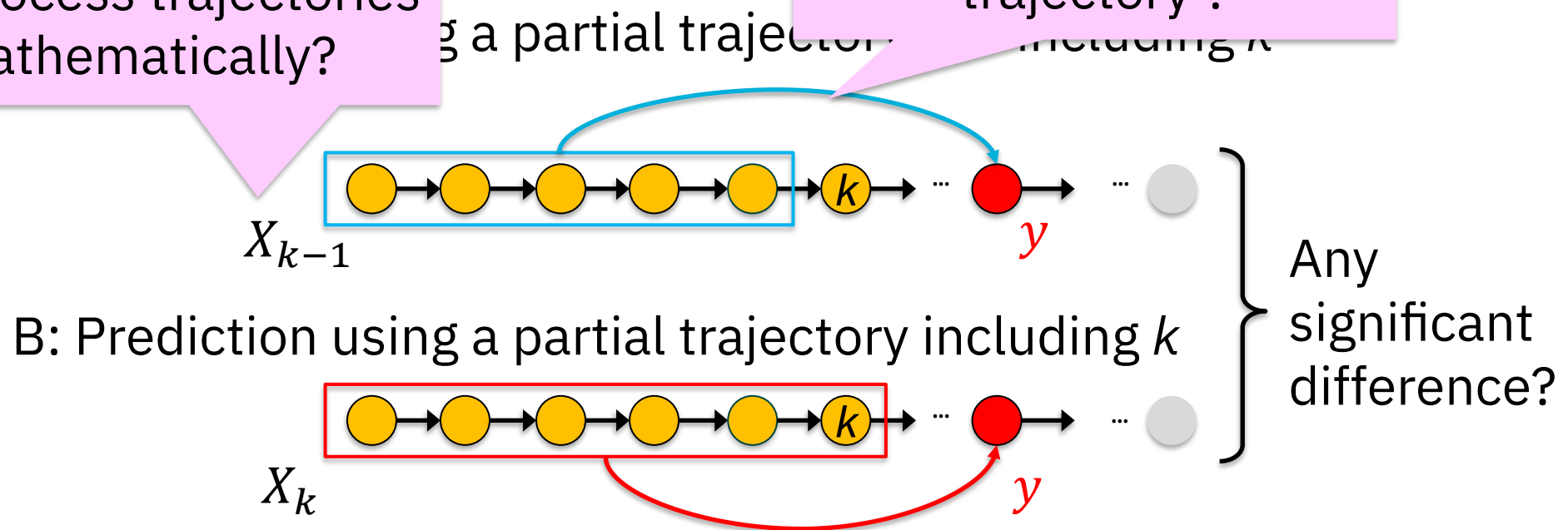
Any significant difference?

Partial trajectory analysis (PTA) approach: Key idea

- PTA computes the attribution score of the k -th process by evaluating the impact of k 's "participation" in the process trajectory.

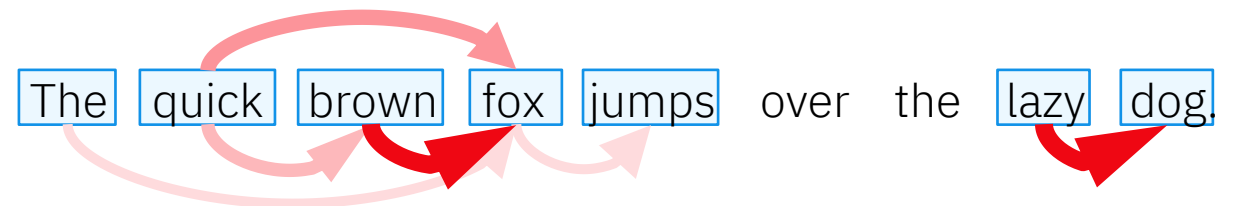
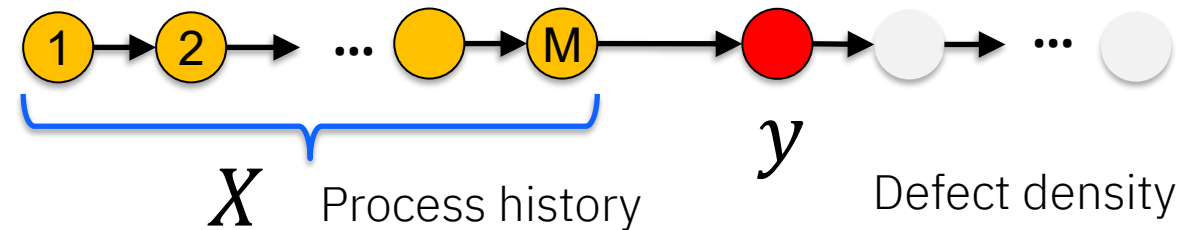
How do we represent the process trajectories mathematically?

How do we predict y from a **partial** process trajectory?



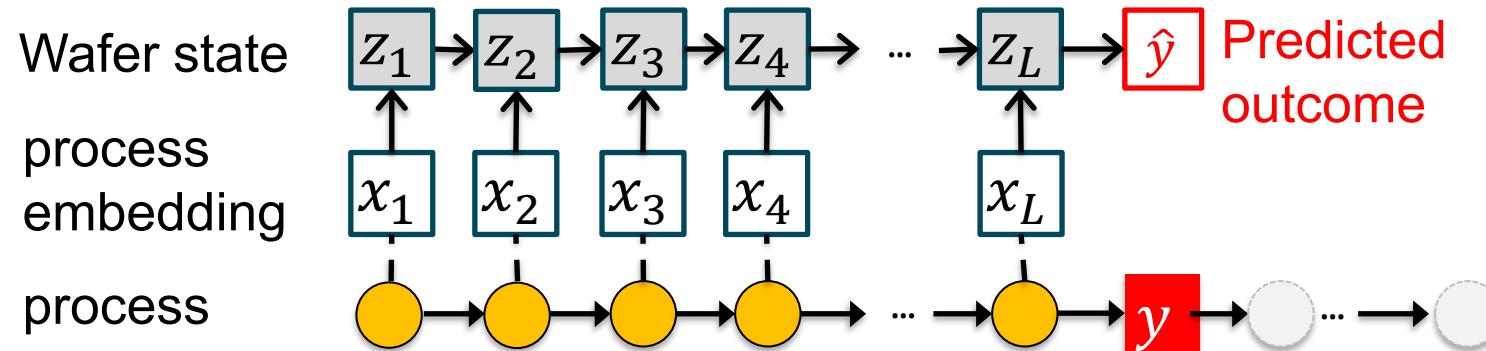
Data assumption and process embedding (“proc2vec”)

- Data $D = \{(X^{(n)}, y^{(n)}) \mid n = 1, \dots, N\}$
 - $X^{(n)}$: process trajectory $(x_1^{(n)}, \dots, x_{L^{(n)}}^{(n)})$. Each process is assumed to have a vector representation (embedding).
 - $y^{(n)}$: Product badness such as defect density (a real number).
- How do we get the embeddings?
 - Create a synthetic word for each
 - ✓ “Process token” = $\text{eqp_id} \oplus \text{recipe_id} \oplus \dots \oplus \text{tool_trace}$
 - Employ a transformer-like approach
 - ✓ [Miyaguchi + ASMC 25]



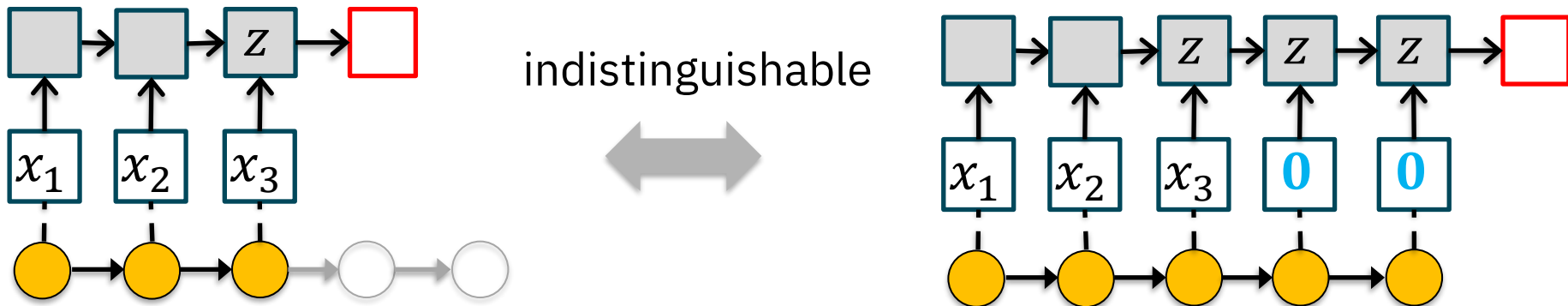
Learning partial trajectory regression model

- Typically, a prediction function has a fixed number of input slots.
 - For 3 processes, it would be like $f(\mathbf{x}_1, \mathbf{x}_2, \mathbf{x}_3)$, a 3-slot function.
 - Hence, cannot handle process trajectories with different lengths.
- State-space model (or RNN) eliminates this limitation
 - Partial prediction by a length- k trajectory: $\hat{y} = f(\mathbf{z}_k = \text{RNN}(\mathbf{x}_1, \dots, \mathbf{x}_k))$
 - ✓ f : A parametric function with trainable parameters
 - ✓ $\mathbf{z}_k$: Latent state vector after observing $\mathbf{x}_k$



Catch: You can't simply zero off downstream processes

- The straightforward use of RNN introduces a significant bias.
- Example:
 - $k=3$ partial prediction is indistinguishable with $k=5$ partial prediction with **zeroed-off input**.
 - i.e., RNN's partial trajectory prediction = full trajectory prediction with a zeroed-off process sequence



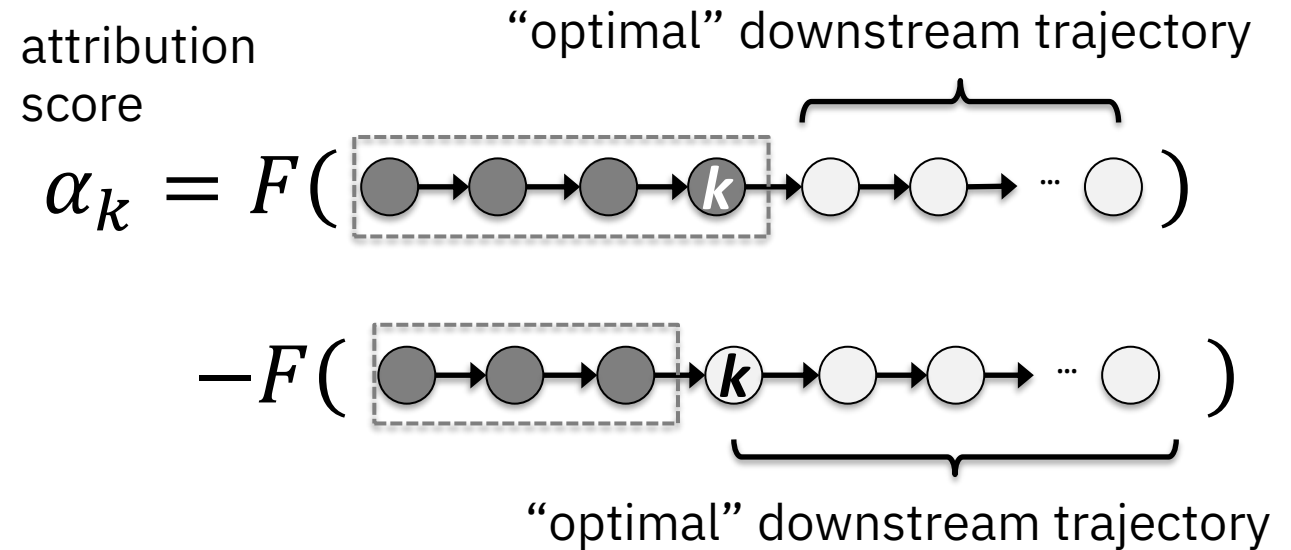
Eliminating the bias of partial trajectory analysis: Potential Loss Analysis (PLA)

- PLA: The attribution score for k is evaluated, given an optimal downstream trajectory:

- $\min_{x_{k+1}, \dots, x_L} F(\mathbf{z}_k, \mathbf{x}_{k+1}, \dots, \mathbf{x}_L)$

- This trajectory optimization problem can be solved by casting it as a reinforcement learning task.

- → Next page



Details→

Ide & Miyaguchi, “Cross-process defect attribution using potential loss analysis,” WSC 25, to appear; <https://arxiv.org/abs/2508.00895>

Formalizing PLA as a reinforcement learning problem (1/2)

- $\min_{\mathbf{x}_{k+1}, \dots} F(\mathbf{z}_k, \mathbf{x}_{k+1}, \dots) = \min_{\mathbf{x}_{k+1}, \dots} \mathbb{E}[\sum_{t=1}^{\infty} C(\mathbf{z}_{k+t}) \mid \mathbf{z}_k]$
 - terminal reward model: $C(\mathbf{z}) = \begin{cases} y(\mathbf{z}), & \mathbf{z} \in (\text{terminal state}) \\ 0, & \text{otherwise} \end{cases}$
- Bellman equation
 - $F^*(\mathbf{z}) \equiv \min_{\mathbf{x}_1, \dots} F(\mathbf{z}, \mathbf{x}_1, \dots) = \min_{\mathbf{x}_1} \{ C(\mathbf{z}) + \underbrace{\sum_{\mathbf{z}_2} p(\mathbf{z}_2 \mid \mathbf{x}_1, \mathbf{z}_1)}_{\text{transition model (assumed deterministic)}} F^*(\mathbf{z}_2) \}$
- The optimization problem we solve (with $F^\theta(\mathbf{z})$ approximating $F^*(\mathbf{z})$):
 - $\max_{\theta} \underbrace{\sum_{\mathbf{z}} \rho(\mathbf{z})}_{\text{empirical density of } \mathbf{z} \text{ (under deterministic assumption)}} F^\theta(\mathbf{z}) \quad \text{s.t.} \quad F^\theta(\mathbf{z}) \leq C(\mathbf{z}) + F^*(\mathbf{z}'), \quad \forall (\mathbf{z} \rightarrow \mathbf{z}'),$

Details→

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Formalizing PLA as a reinforcement learning problem (2/2)

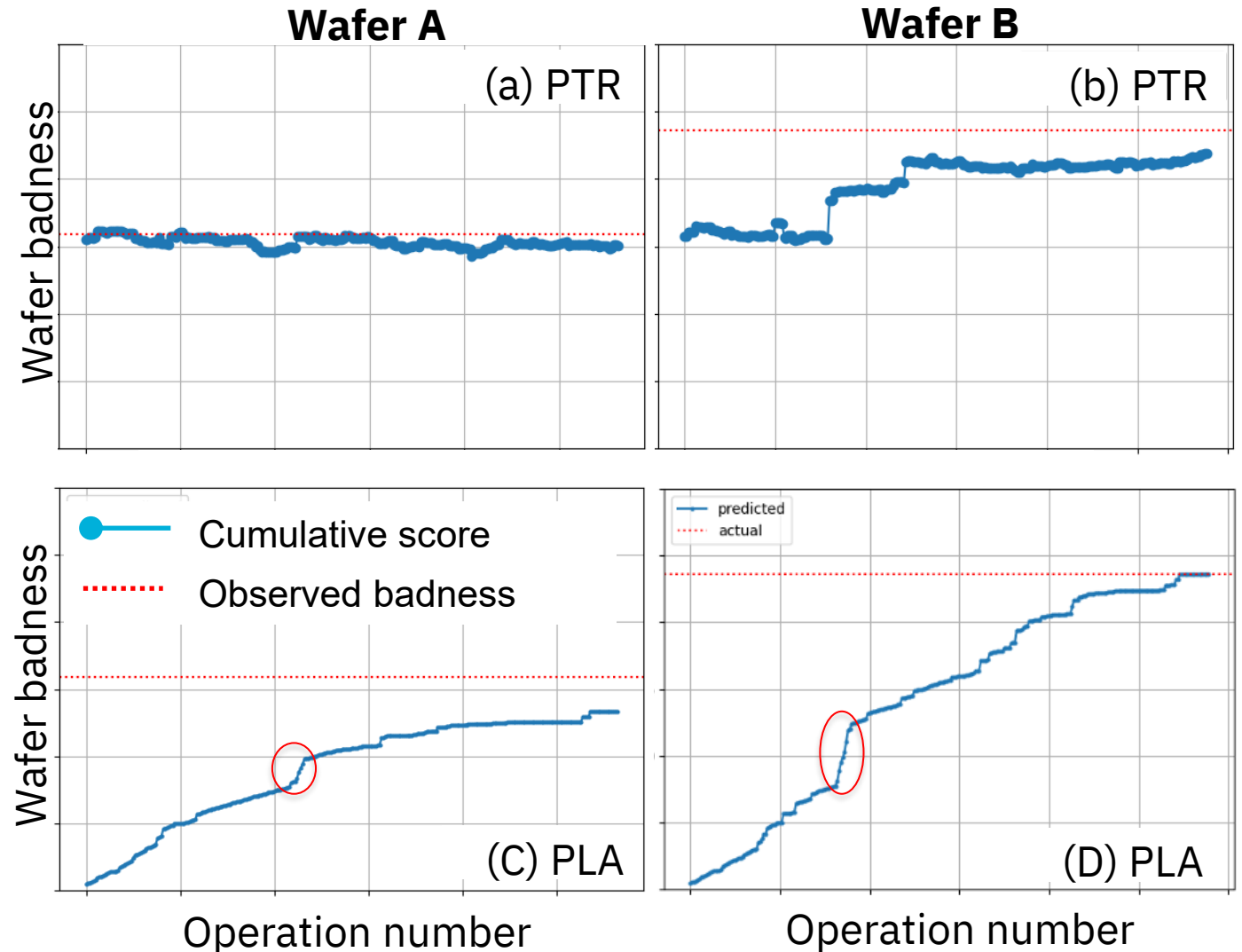
- Final objective function to be maximized

- $$R(\theta \mid \mu) = \frac{1}{N} \sum_{n=1}^N \left[\frac{\mu}{L^{(n)}} \sum_{t=1}^{L^{(n)}} F^{\theta} \left(\mathbf{z}_t^{(n)} \right) - \underbrace{\frac{1}{2} \left\{ y^{(n)} - F^{\theta} \left(\mathbf{z}_{L^{(n)}}^{(n)} \right) \right\}^2}_{\text{squared loss}} - \frac{1}{2} \sum_{t=1}^{L^{(n)}-1} \left\{ F^{\theta} \left(\mathbf{z}_{t+1}^{(n)} \right) - F^{\theta} \left(\mathbf{z}_t^{(n)} \right) \right\}^2 \right]$$

- This provides the partial prediction function and attribution model simultaneously.
- The time difference of the F function can be directly parameterized:
 - $G^{\theta}(\mathbf{z}_t, \mathbf{z}_{t-1}) \equiv F^{\theta}(\mathbf{z}_t) - F^{\theta}(\mathbf{z}_{t-1}) = \text{ReLU}_{\theta}(\mathbf{z}_t \oplus \mathbf{z}_{t-1})$
 - This function provides the attribution score for the k-th process.

2nm conductor process defect diagnosis example

- The graphs plot the cumulative attribution score.
 - Big jump = likely root cause
 - The model was trained with 727 wafers.
- PTR approach does not provide meaningful signals.
- PLA successfully detects likely root cause
 - In this case, they correspond to too long waiting hours at a certain piece of equipment.



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